

# PATENT ABSTRACTS OF JAPAN

(11)Publication number : 05-055133

(43)Date of publication of application : 05.03.1993

(51)Int.Cl. H01L 21/027  
B05B 1/14

(21)Application number : 04-009078 (71)Applicant : TOKYO ELECTRON LTD  
TOKYO ELECTRON KYUSHU KK

(22)Date of filing : 22.01.1992 (72)Inventor : HASEBE KEIZO  
TATEYAMA KIYOHISA  
MATSUYAMA YUJI  
NAKAHARA TETSUO  
KIMURA YOSHIO

## (30)Priority

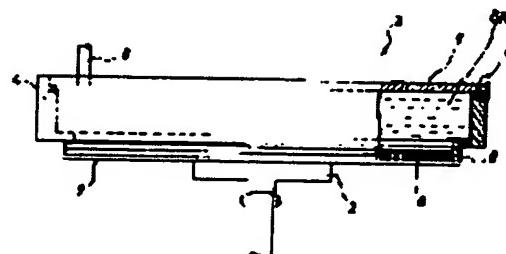
Priority number : 03 6369 Priority date : 23.01.1991 Priority country : JP

## (54) LIQUID SUPPLY NOZZLE

### (57)Abstract:

**PURPOSE:** To provide a liquid supplying nozzle which supplies the prescribed liquid rapidly in a short time without giving impact a subject to be processed and without generating bubbles and that efficiently processes with a small quantity of liquid.

**CONSTITUTION:** A liquid supplying nozzle 3 provided on the top of a spin chuck 2 which supports a semiconductor wafer 1 is provided with a short container- shaped liquid storing part 4 and many fine holes 6 at the bottom of the liquid storing part 4. Then, the prescribed developer is supplied into the liquid storing part 4 at the prescribed pressure from a developer supplying pipe 8 and the developer is supplied to the semiconductor wafer 1 by bleeding the developer



from the many fine holes 6.

#### LEGAL STATUS

[Date of request for examination] 27.09.1996  
[Date of sending the examiner's decision of rejection]  
[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]  
[Date of final disposal for application]  
[Patent number] 2816510  
[Date of registration] 21.08.1998  
[Number of appeal against examiner's decision of rejection]  
[Date of requesting appeal against examiner's decision of rejection]  
[Date of extinction of right]